Page 1 of 2

INFORMATION DISCLOSURE STATEMENT

Atty. Docket No.: 110.0142 0101

Applicant(s): ZHAN et al.

Application Filing Date: 18 October 2000

Group: 2877

Information Disclosure Statement mailed: March 9, 2004

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U.S. PATENT DOCUMENTS

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nitial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
MP	4,893,932	01/16/90	Knollenberg	_		
los	5,220,403	06/15/93	Batchelder et al.			
MP	5,822,073	10/13/98	Yee et al.			
ASP	5,991,488	11/23/99	Salamon et al.			
1878	6,127,183	10/03/00	Ivarsson et al.			
M	6,493,097	12/10/02	Ivarsson		->	
UPP	6,594,011	07/15/03	Kempen			

FOREIGN PATENT DOCUMENTS

Examiner	Document Number	Date	Country	Class	Subclass	Trans	lation
Initial						Yes	No
		///	1/10				
							l

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Document Description
W	Azzam, "Differential reflection phase shift under conditions of attenuated internal reflection," J. Opt. Soc. Am. A, 1999;16(7):1700-1702.
m	Bu-Abbud et al., "Characterization of Fabrication Damage in SrTiO ₃ by Internal and External Measurements," <i>Surface Science</i> , 1980;96:329-345.
MP	Burshta et al., "Ellipsometry of guided wave polaritons at solid surfaces," Surface Science, 1994;301:399-404.
m	Ikeda et al., "Molecular orientation near the surface of a smectic liquid crystal cell showing V-shaped switching by means of attenuated total internal reflection ellipsometry," <i>Physical Review E</i> ; 2001;63:061703-1-7.
Ap	Irene, "Ultra-thin SiO ₂ film studies: index, thickness, roughness and the initial oxidation regime," Solid State Electronics, 2001;45:1207-1217.

EXAMINER	Mhu	Date Considered 4/26/64
		t citation is in conformance with MPEP 609; Draw line through citation if not in

INFORMATION
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STATEMENT

Atty. Docket No.: 110.0142 0101 Serial No.: 09/691,006

Applicant(s): ZHAN et al. Confirmation No.: 4510

Application Filing Date: 18 October 2000 Group: 2877

Document Description

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Information Disclosure Statement mailed: March 9, 2004

MAR	O RUES P (<u></u>	
& _	Examined Initials		
₹8 11	ADE MARK		Johansen et al., "Imaging surfac
	MP		wavelengths: Sensitivity considerable 2000;71(9):3530-3538.

HP	Johansen et al., "Imaging surface plasmon resonance sensor based on multiple wavelengths: Sensitivity considerations," <i>Review of Scientific Instruments</i> , 2000;71(9):3530-3538.
M	Moy, "Immersion ellipsometry," Applied Optics, 1981;20(22):3821-3822.
IMP	Pokrowsky, "Optical methods for thickness measurements on thin metal films," <i>Applied Optics</i> , 1991;30(22):3228-3232.
M	Takabayashi et al., "Propagation length of guided waves in lossy Si film sandwiched by identical dielectrics," J. Opt. Soc. Am. B, 1995;12(12):2406-2411.
m	Tiwald et al., "Determination of the mid-IR optical constants of water and lubricants using IR ellipsometry combined with an ATR cell," <i>Thin Solid Films</i> , 1998;313-314:718-721.
HP	Yablonskii et al., "Control of the bias tilt angles in nematic liquid crystals," <i>J. Appl. Phys.</i> , 1999;85(5):2556-2561.

EXAMINER Date Considered 4/26/07

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE STATEMENT

Atty. Docket No.: 110.0142 0101	Serial No.: 09/691,006		
Applicant(s): ZHAN et al.	Confirmation No.: 4510		
Application Filing Date: 18 October 2000	Group: 2877		
Information Disclosure Statement mailed: November 7, 2003			

U.S. PATENT DOCUMENTS

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Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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FOREIGN PATENT DOCUMENTS

Examiner		Document Number	Date	Country	Class	Subclass	Trans	lation
Initial							Yes	No
				MML				
			!	10.				
	j							

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Document Description
Zhan et al., "High-Resolution Imaging Ellipsometer", Applied Optics, 2002; 41(22):4443-4450.
Zhan et al., "Near-Field Nano-Ellipsometer for Ultrathin Film Characterization", Journal of Microscopy, 2003;210:214-219.
Zhan, "Novel Polarization Measurement and Manipulation Techniques for Nanometer Scale Applications", Thesis, University of Minnesota, August 2002; title pages, Acknowledgement, Abstract, and Table of Contents only:12 pgs.
Zhan, "Radiation Forces on a Dielectric Sphere Produced by Highly Focused Cylindrical Vector Beams", <i>Journal of Optics A: Pure and Applied Optics</i> , 2003; 5:229-232.
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EXAMINER //	Date Considered		
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